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THE THICKNESS OF SnO₂: F FILMS AS PRINCIPAL FACTOR OF THEIR PROPERTIES*

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All of the studied properties of SnO₂: F films prepared by spraying of ethanol solution of SnCl₄ · 5H₂O onto heated glass substrates (Ts = 300°C, 400°C, 430°C) in ambient air atmosphere (spreying angle α = 45°, airless sprayer-to-substrate distance of ≈ 50 cm) strongly depend on the film thickness d.

At given substrate temperature of preparation, the thickness dependences of the: refractive index n(d), optical gap Eg(d), and X-ray diffraction intensities ratio $\frac{I(hkl)}{I(200)}$ (d) (hkl = 110, 211, 301) exhibit minimum at a concrete film thickness d = d_f. The thickness dependences of the electrical conductivity σ(d) and the Haacke's „figure of merit“ Φ(d) (Φ = T¹⁰/R□; T—transmittance, R□ — sheet resistance) obtain maximums at the same thickness d_f.

INTRODUCTION

Our first results were concerned to SnO₂: F films [1] prepared by spraying of ethanol solution of SnCl₄ · nH₂O (200gr SnCl₄ · nH₂O 90ml C₂H₅OH 10ml HCl 2.8ml 50%HF; F/Sn=0.147; solution A) in intervals 1—2s with pauses of about 60s in between A distance airless sprayer-to-substrate of ≈ 50 cm and a spraying angle of ≈ 45° were used together with substrate temperature Ts = 430°C. The experimental results pointed out the thickness dependence of n, Φ, σ i.e. for d ≈ 0.85 μm n(d), Φ(d) and σ(d) obtain maximums.

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The next study [2] was dealing mainly with the sprayed $\text{SnO}_2 : \text{F}$ films prepared with ethanol solution of $\text{SnCl}_4 \cdot 5\text{H}_2\text{O}$ (200gr $\text{SnCl}_4 \cdot 5\text{H}_2\text{O}$, 90ml $\text{C}_2\text{H}_5\text{OH}$, 10ml HCl , 2.8ml 50% HF ; solution A') at $T_s = 300^\circ\text{C}$, 400°C , and 430°C . In that case $n(d)$ for all the films exhibit minimums for $d=d_f$, while $\sigma(d)$ and $\Phi(d)$ exhibit maximums. $d_f = 0.6 - 0.8 \mu\text{m}$ is different for different T_s . The comparison of the film properties prepared with solutions A and A' was performed together with sprayed undoped SnO_2 films (solution A': 200gr $\text{SnCl}_4 \cdot 5\text{H}_2\text{O}$, 90ml $\text{C}_2\text{H}_5\text{OH}$, 10ml HCl ; $T_s = 430^\circ\text{C}$). It affirmed the best transparent-conductive properties of the films prepared with solution A.

The results presented in this work (sol. A'), i.e. $n(d)$, $\Phi(d)$, $\sigma(d)$, $E_g(d)$ and $\frac{I(hkl)}{I(200)} \sim (d)$ certify more completely the thickness dependence of the film properties.

2. EXPERIMENTAL RESULTS

a. — From the spectral transmittance measurements $T(\lambda)$ (spectrophotometer Pye Unicam SPG—300) and their interference maxima and minima, the spectral refractive index $n(\lambda)$ and the film thickness d have been determined [3].

The plots of $n(d)$ for the studied films prepared at substrate temperatures $T_s = 300^\circ\text{C}$, 400°C and 430°C are given in Fig. 1. Minimums in the courses of $n(d)$ for $d=d_f$ are well expressed. d_f is different for different T_s . The values of n are smaller than those reported in some former investigations [4—6].

b. — The optical gap was determined from the spectral absorptivity $\alpha(\lambda)$ i.e. $T(\lambda)$ measurements using the relation $(\alpha_{\nu}h\nu)^2 = \text{const.}(h\nu - E_g)$ plotted as $(\alpha_{\nu}h\nu)^2$ v.s. $h\nu$ [7].

The plots $E_g(d)$ for the studied films are presented in Fig. 2. It is notable that the minimums in their courses correspond to those of $n(d)$ (Fig. 1). All the E_g values are lower than the previously reported ones [4,8,9].

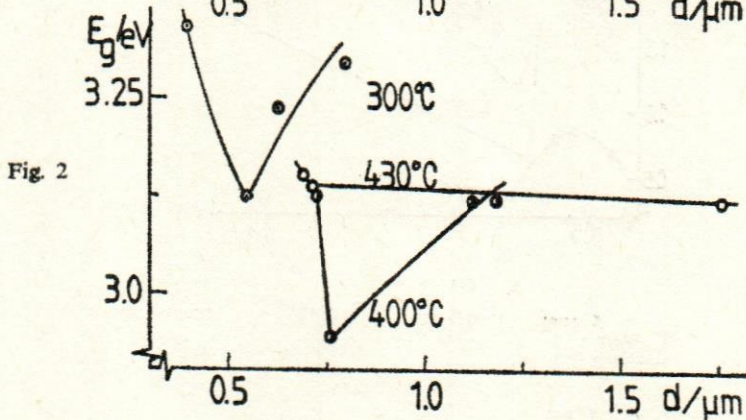
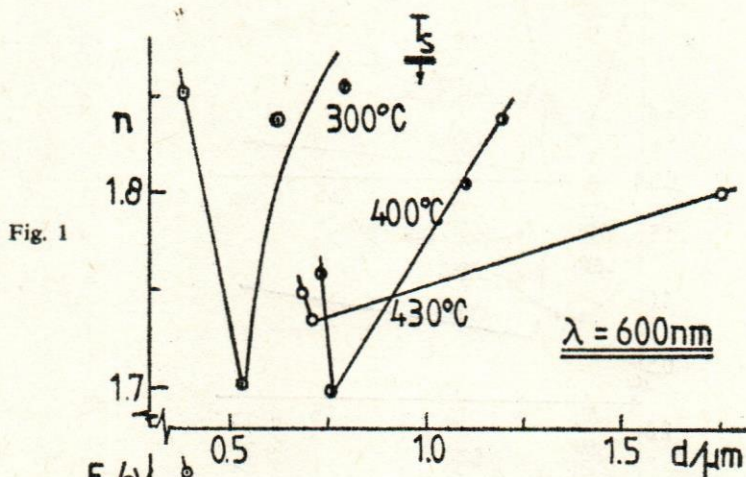
c. — Some results of the X-ray diffraction measurements ($\text{Cu K}\alpha$; $\lambda = 1.54\text{\AA}$; JEOL JDX—7E) for the investigated films are presented in Fig. 3 in form of intensity ratios $\frac{I(hkl)}{I(200)}(d)$ where $hkl=110, 211, 301$. These diffraction peaks were chosen referring to some previous reports [4,9 — 12] where they are shown to be the most pronounced lines.

The comparison of the plots in Figs. 1, 2 and 3 shows an obvious similarity i.e. they obtain minimums for the same film thickness $d=d_f$.

The minimums in $\frac{I(hkl)}{I(200)}(d)$ indicate that the differences between the compared intensities are the smallest when $d=d_f$. For this film thickness the preferred orientation of the crystallites diminishes.

In Fig. 3d are given two X ray diffractograms ($T_s = 300^\circ\text{C}$; $d=0.54\ \mu\text{m}$, and $0.79\ \mu\text{m}$). Diffraction A ($2\theta = 31,4^\circ$) from [15] is ascribed to the presence of suboxides (SnO , Sn_2O_3 , Sn_3O_4)

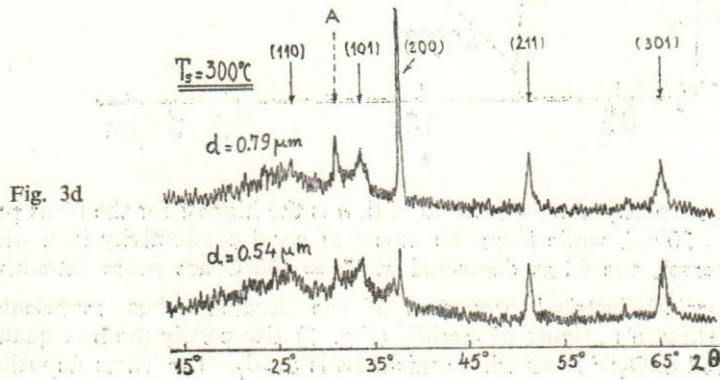
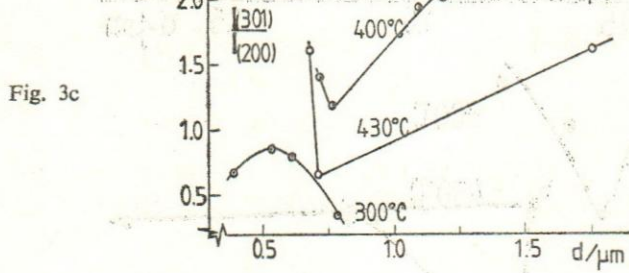
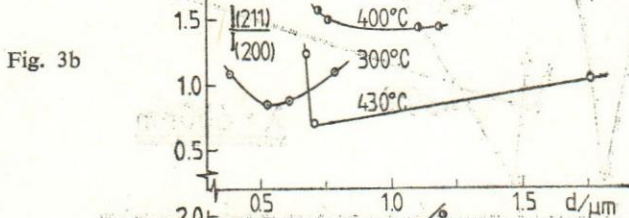
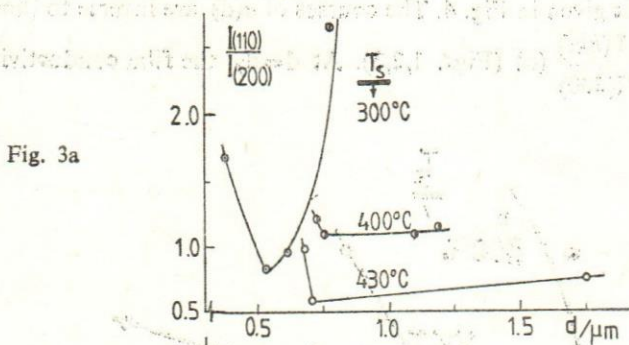
d.— The thickness dependence of the film conductivity (measured by the four point method) is given in Fig. 4. The courses of $\sigma(d)$ are inverse to those of $n(d)$, $E_g(d)$ and $\frac{I(hkl)}{I(200)}$ (d) (Figs. 1,2,3). At $d=d_f$ the film conductivity

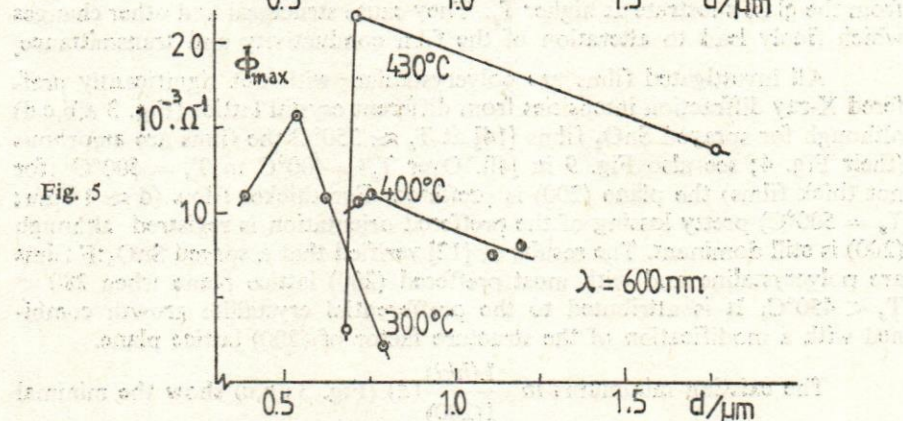
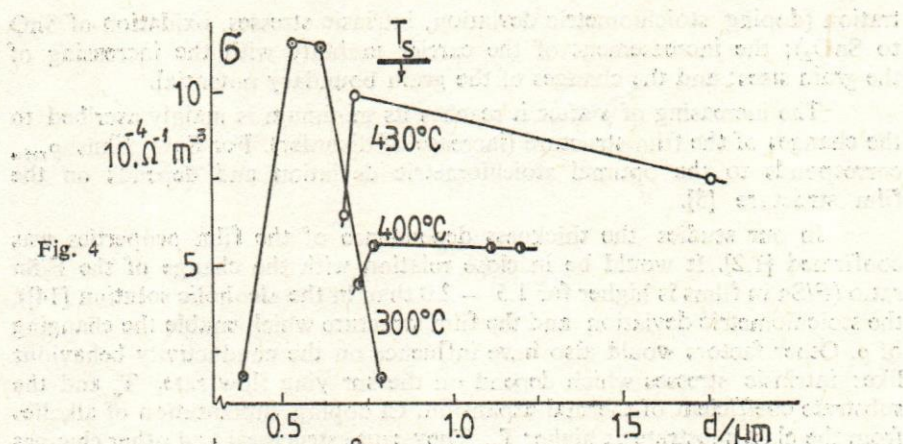


is maximal. In a pretty narrow interval of d , σ is the highest for the films prepared at $T_s = 300^\circ\text{C}$, while from the aspect of good conductivity in a wide thickness interval, the films deposited at $T_s = 430^\circ\text{C}$ are more attractive.

e.— The optical-electrical properties of the studied films represented through the Haacke's „figure of merit” (Fig. 5) also certify the best quality of the sprayed SnO₂:F films whose thickness is $d=d_f$. The films deposited

at $T_s = 430^\circ\text{C}$ are preferable. The presented plots $\Phi_{max}(d)$ correspond to T_{max} of the interference maximums in $T(\lambda)$, ($\Phi_{max} = \frac{T_{max}^{10}}{R_{\square}}$).





DISCUSSION

The previous studies (4,5,13) of sprayed SnO₂ films verified the existence of minimums in $\rho(T_s)$ [5] and $R_{\square}(T_s)$ [13] which correspond to the maximums in Sn concentration \bar{c} [4] i.e. to the maximal concentration of oxygen vacancies O^{2+} .

The resistivity ρ exhibits similar behaviour as a function of the dopant concentration [14,4]. Namely, ρ obtains a minimum [at specific dopant concentration $[F]/[Sn]$ at. ≈ 0.25 .

The resistivity dependence of the oxygen flow rate f (C.V.D. method) [15] possesses a minimum at $f \approx 1.8$ lit/min. Because of the established linearity between the film thickness d and the flow rate f , ρ_{min} is found to correspond to a concrete value of d . The decreasing of ρ (increasing of σ) before it attains its minimum is ascribed to: the increasment of the carrier concen-

tration (doping stoichiometric deviation, intrinsic stresses, oxidation of SnO to SnO₂); the increase of the carrier mobility with the increasing of the grain sizes; and the changes of the grain boundary potential.

The increasing of ρ after it reaches its minimum is mainly ascribed to the changes of the film structure (increase of disorder). For SnO₂ films ρ_{min} corresponds to the optimal stoichiometric deviation and depends on the film structure [5].

In our studies the thickness dependence of the film properties was confirmed [1,2]. It would be in close relation with the change of the F/Sn ratio (F/Sn in films is higher for 1.5 — 2.0 than in the alcoholic solution [14]), the stoichiometric deviation and the film structure which enable the changing of ρ . Other factors would also have influence on the conductivity behaviour like: intrinsic stresses which depend on the spraying flow rate, T_s and the substrate coefficient of thermal expansion, Cl doping, implantation of alkalis from the glass substrate at higher T_s . They cause structural and other changes which finally lead to alteration of the film conductivity and transmittance.

All investigated films are polycrystalline with not significantly preferred X-ray diffraction intensities from different crystal lattice (Fig. 3 a,b,c,d) although for sprayed SnO₂ films [14] at $T_s \approx 350^\circ\text{C}$ the films are amorphous (their Fig. 4; see also Fig. 9 in [4]). Over $T_s = 400^\circ\text{C}$ to $T_s = 500^\circ\text{C}$ (for not thick films) the plane (200) is preferred. For thicker films ($d \approx 1.5\mu\text{m}$; $T_s = 500^\circ\text{C}$) pretty lossing of the preferred orientation is registered although (200) is still dominant. The results of [12] verified that a sprayed SnO₂:F films are polycrystalline and with most preferred (200) lattice plane when $280 < T_s < 450^\circ\text{C}$. It is attributed to the preferential crystallite growth combined with a modification of the structure factor of (200) lattice plane.

The existing minimums in $\frac{I(hkl)}{I(200)}$ (d) (Fig. 3a,b,c) show the minimal differences between the compared X-ray diffraction intensities (fig. 3d) and it would correspond to the optimal doping of F/Sn and Cl/Sn and optimal stoichiometric deviation when at $d=d_f\sigma_{max}$ is obtained (Fig. 4).

The behaviour of n depends on the film structure which is expressed not only in the courses of $n(\lambda)$ but also in the values of n . The polycrystalline sprayed SnO₂ films [5] have smaller n than the amorphous ones prepared by flash evaporation ($n=2.15$). The similarity in the courses of n (d) (Fig. 1) and $\frac{I(hkl)}{I(200)}$ (d) (Fig. 3 a,b,c) and the obtained σ_{max} (Fig. 4) for $d=d_f$ would relate to the condition when optimum in the processes of doping, oxidation stoichiometric deviation and order/disorder is achieved in the films.

The optical gap E_g for sprayed SnO₂ films is between 3.7 — 3.8 eV (for single crystal $E_g = 3.6$ eV) [4]. For sprayed SnO₂ films $E_g = 3.7\text{eV}$ was registered and $E_g = 2.4\text{eV}$ for flash evaporated films [5]. By doping (Sb) [9,17] E_g increases by increasing of the dopant concentration ($E_g = 3.95$ — 4.62 eV).

In our case (Fig. 2) E_g would be in relation with the film structure. $E_{g,min}$ would correspond to optimums between order/ disorder, when also the dopant concentration, stoichiometric deviation and the film structure are optimal (σ_{max}).

Films with σ_{max} posses maximal transmitivity T. It is (Fig. 5) expressed by $\Phi(d)_{max}$ when $d=d_f$ is obtained.

CONCLUSION

Thickness dependence of SnO₂:F film properties prepared by the described procedure and spraying conditions enable concretisation of the film thickness $d=d_f$ when the transparent-conductive properties of SnO₂:F films are the ebest.

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ДЕБЕЛИНАТА НА $\text{SnO}_2\text{:F}$ ФИЛМОВИ — ГЛАВЕН ФАКТОР ЗА НИВНИТЕ ОСОБИНИ

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и В. Јорданова

Експерименталните резултати од испитуваните $\text{SnO}_2\text{:F}$ филмови добиени со спреирање при три температури на субстратот ($T_s = 300, 400$ и 430°C) и останатите назначени параметри на спреирањето покажуваат дека: 1.- индексот на прекршувањето n (Fig. 1); 2.— оптичката енергија на зафаќањето E_g (Fig. 2), 3.— односот на интензитетите на дифрагираните рентгенски зраци од поедини равнини ($I_{(h,k,l)}/I_{(200)}$) т.е. ($I_{(h,k,l)}/I_{(200)}$) (Fig. 3a,b,c,d), 4.— електричната проводливост σ (Fig. 4) и 5.— Хааске-овиот „figure merit“ $\Phi = \frac{T^{10}}{R}$ (Fig. 5) силно

зависат од дебелината на филмот постигајќи минимум, односно максимум, при определена дебелина на филмот $d=d_f$. d_f е во функција од температурата на субстратот T_s .

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